



511.40998X00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: N. KOYAMA, et al.
Application No.: 10/081,188
Filed: December 18, 2001
For: CMP ABRASIVE, METHOD FOR POLISHING SUBSTRATE
AND METHOD FOR MANUFACTURING SEMICONDUCTOR
DEVICE USING THE SAME, AND ADDITIVE FOR COMP
ABRASIVE
Art Unit: 3724
Examiner: T. V. Eley

RESPONSE

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

March 22, 2005

Sir:

In response to the Office Action mailed November 22, 2004, Applicants respectfully elect the Group I claims, claims 1-9, 12-17 and 20-22, which the Examiner contends are drawn to a CMP abrasive and additive, for prosecution on the merits in the above-identified application. This election is made without traverse.

Examination of the Group I claims, on the merits, in due course, is respectfully requested.

If the Examiner believes that there are any other points which may be clarified or otherwise disposed of either by telephone discussion or by personal interview, the Examiner is invited to contact Applicants' undersigned attorney at the number indicated below.

To the extent necessary, Applicants petition for an extension of time under 37 CFR 1.136. Please charge any shortage in fees due in connection with the filing of

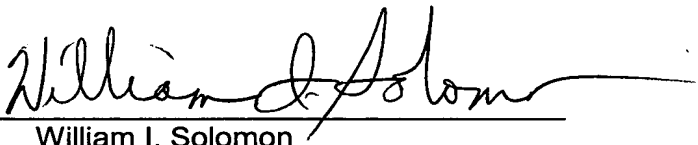
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this paper, including extension of time fees, to the Antonelli, Terry, Stout & Kraus, LLP Deposit Account No. 01-2135 (Docket No. 511.40998X00), and please credit any excess fees to such deposit account.

Respectfully submitted,

ANTONELLI, TERRY, STOUT & KRAUS, LLP

By 
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Reg. No. 28,565

WIS/dlt

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